

ABSTRACT

A piezoelectric vibrator of the present invention has a laminated structure where silicon oxide films (3) having substantially the same thickness are disposed at both faces of piezoelectric plate (1) as dielectric films. Using
5 the structure discussed above, because dielectric films are formed at the both faces of piezoelectric plate (1), a difference of internal stress, which is caused by a difference of stress relaxation in a long term and affects piezoelectric plate (1) or the dielectric film, becomes small. Therefore, a warp can be considerably small. As a result, a change, which is caused by the warp of the piezoelectric
10 vibrator, in a resonance frequency of the piezoelectric vibrator can be small.